

# INTERNATIONAL STANDARD

## NORME INTERNATIONALE



**Semiconductor devices – Micro-electromechanical devices –  
Part 32: Test method for the nonlinear vibration of MEMS resonators**

**Dispositifs à semiconducteurs – Dispositifs microélectromécaniques –  
Partie 32: Méthode d'essai pour la vibration non linéaire des résonateurs MEMS**



## THIS PUBLICATION IS COPYRIGHT PROTECTED

Copyright © 2019 IEC, Geneva, Switzerland

All rights reserved. Unless otherwise specified, no part of this publication may be reproduced or utilized in any form or by any means, electronic or mechanical, including photocopying and microfilm, without permission in writing from either IEC or IEC's member National Committee in the country of the requester. If you have any questions about IEC copyright or have an enquiry about obtaining additional rights to this publication, please contact the address below or your local IEC member National Committee for further information.

Droits de reproduction réservés. Sauf indication contraire, aucune partie de cette publication ne peut être reproduite ni utilisée sous quelque forme que ce soit et par aucun procédé, électronique ou mécanique, y compris la photocopie et les microfilms, sans l'accord écrit de l'IEC ou du Comité national de l'IEC du pays du demandeur. Si vous avez des questions sur le copyright de l'IEC ou si vous désirez obtenir des droits supplémentaires sur cette publication, utilisez les coordonnées ci-après ou contactez le Comité national de l'IEC de votre pays de résidence.

IEC Central Office  
3, rue de Varembe  
CH-1211 Geneva 20  
Switzerland

Tel.: +41 22 919 02 11  
[info@iec.ch](mailto:info@iec.ch)  
[www.iec.ch](http://www.iec.ch)

### About the IEC

The International Electrotechnical Commission (IEC) is the leading global organization that prepares and publishes International Standards for all electrical, electronic and related technologies.

### About IEC publications

The technical content of IEC publications is kept under constant review by the IEC. Please make sure that you have the latest edition, a corrigendum or an amendment might have been published.

#### IEC publications search - [webstore.iec.ch/advsearchform](http://webstore.iec.ch/advsearchform)

The advanced search enables to find IEC publications by a variety of criteria (reference number, text, technical committee,...). It also gives information on projects, replaced and withdrawn publications.

#### IEC Just Published - [webstore.iec.ch/justpublished](http://webstore.iec.ch/justpublished)

Stay up to date on all new IEC publications. Just Published details all new publications released. Available online and once a month by email.

#### IEC Customer Service Centre - [webstore.iec.ch/csc](http://webstore.iec.ch/csc)

If you wish to give us your feedback on this publication or need further assistance, please contact the Customer Service Centre: [sales@iec.ch](mailto:sales@iec.ch).

#### Electropedia - [www.electropedia.org](http://www.electropedia.org)

The world's leading online dictionary on electrotechnology, containing more than 22 000 terminological entries in English and French, with equivalent terms in 16 additional languages. Also known as the International Electrotechnical Vocabulary (IEV) online.

#### IEC Glossary - [std.iec.ch/glossary](http://std.iec.ch/glossary)

67 000 electrotechnical terminology entries in English and French extracted from the Terms and Definitions clause of IEC publications issued since 2002. Some entries have been collected from earlier publications of IEC TC 37, 77, 86 and CISPR.

### A propos de l'IEC

La Commission Electrotechnique Internationale (IEC) est la première organisation mondiale qui élabore et publie des Normes internationales pour tout ce qui a trait à l'électricité, à l'électronique et aux technologies apparentées.

### A propos des publications IEC

Le contenu technique des publications IEC est constamment revu. Veuillez vous assurer que vous possédez l'édition la plus récente, un corrigendum ou amendement peut avoir été publié.

#### Recherche de publications IEC - [webstore.iec.ch/advsearchform](http://webstore.iec.ch/advsearchform)

La recherche avancée permet de trouver des publications IEC en utilisant différents critères (numéro de référence, texte, comité d'études,...). Elle donne aussi des informations sur les projets et les publications remplacées ou retirées.

#### IEC Just Published - [webstore.iec.ch/justpublished](http://webstore.iec.ch/justpublished)

Restez informé sur les nouvelles publications IEC. Just Published détaille les nouvelles publications parues. Disponible en ligne et une fois par mois par email.

#### Service Clients - [webstore.iec.ch/csc](http://webstore.iec.ch/csc)

Si vous désirez nous donner des commentaires sur cette publication ou si vous avez des questions contactez-nous: [sales@iec.ch](mailto:sales@iec.ch).

#### Electropedia - [www.electropedia.org](http://www.electropedia.org)

Le premier dictionnaire d'électrotechnologie en ligne au monde, avec plus de 22 000 articles terminologiques en anglais et en français, ainsi que les termes équivalents dans 16 langues additionnelles. Egalement appelé Vocabulaire Electrotechnique International (IEV) en ligne.

#### Glossaire IEC - [std.iec.ch/glossary](http://std.iec.ch/glossary)

67 000 entrées terminologiques électrotechniques, en anglais et en français, extraites des articles Termes et Définitions des publications IEC parues depuis 2002. Plus certaines entrées antérieures extraites des publications des CE 37, 77, 86 et CISPR de l'IEC.

# INTERNATIONAL STANDARD

## NORME INTERNATIONALE



**Semiconductor devices – Micro-electromechanical devices –  
Part 32: Test method for the nonlinear vibration of MEMS resonators**

**Dispositifs à semiconducteurs – Dispositifs microélectromécaniques –  
Partie 32: Méthode d'essai pour la vibration non linéaire des résonateurs MEMS**

INTERNATIONAL  
ELECTROTECHNICAL  
COMMISSION

COMMISSION  
ELECTROTECHNIQUE  
INTERNATIONALE

ICS 31.080.99

ISBN 978-2-8322-6455-3

**Warning! Make sure that you obtained this publication from an authorized distributor.  
Attention! Veuillez vous assurer que vous avez obtenu cette publication via un distributeur agréé.**

## CONTENTS

FOREWORD.....	3
1 Scope.....	5
2 Normative references .....	5
3 Terms and definitions .....	5
4 Test parameters of nonlinear vibration of the resonators .....	5
5 Test method for the amplitude-frequency response and phase-frequency response of the nonlinear vibration .....	6
5.1 Test system .....	6
5.2 Test conditions .....	6
5.3 Test procedures.....	7
6 Test method for the bending factor of the nonlinear vibrating frequency response .....	7
7 Test method for the amplitude threshold for the nonlinear jump .....	7
8 Test method for the frequency deviation as a result of the nonlinear vibration .....	8
8.1 Frequency deviation of the self-excitation closed-loop system .....	8
8.2 Frequency deviation of the phase-locked closed-loop system .....	8
8.3 Frequency deviation of the burst-excited system.....	9
Annex A (normative) Model of nonlinear vibration of MEMS resonators and bending factor .....	10
A.1 Model of nonlinear vibration of MEMS resonator .....	10
A.2 Solution of the nonlinear vibration model .....	11
A.3 Bending factor of the amplitude-frequency response .....	11
Annex B (informative) Nonlinear jump of the frequency response of MEMS resonators .....	14
Annex C (normative) Frequency deviation of MEMS resonators in the closed-loop system.....	16
C.1 Effect of the frequency deviation of the MEMS resonator on the accuracy of the resonant sensor .....	16
C.2 Frequency deviation of the self-exciting closed-loop system .....	16
C.3 Frequency deviation of the phase-locked closed-loop system .....	16
C.4 Oscillation frequency deviation of the burst-excited closed-loop system .....	18
Figure 1 – Test system .....	6
Figure 2 – 3 dB bandwidth of the linear amplitude-frequency response .....	8
Figure A.1 – Typical amplitude-frequency response of the nonlinear vibration of the MEMS resonator .....	12
Figure A.2 – Change of the amplitude-frequency response with the bending factor .....	13
Figure B.1 – Jump phenomenon of the frequency response of a clamped-clamped MEMS bridge resonator .....	14
Figure B.2 – Three nonlinear amplitude-frequency responses with various amplitude level ...	15

## INTERNATIONAL ELECTROTECHNICAL COMMISSION

**SEMICONDUCTOR DEVICES –  
MICRO-ELECTROMECHANICAL DEVICES –**

**Part 32: Test method for the nonlinear vibration of MEMS resonators**

**FOREWORD**

- 1) The International Electrotechnical Commission (IEC) is a worldwide organization for standardization comprising all national electrotechnical committees (IEC National Committees). The object of IEC is to promote international co-operation on all questions concerning standardization in the electrical and electronic fields. To this end and in addition to other activities, IEC publishes International Standards, Technical Specifications, Technical Reports, Publicly Available Specifications (PAS) and Guides (hereafter referred to as "IEC Publication(s)"). Their preparation is entrusted to technical committees; any IEC National Committee interested in the subject dealt with may participate in this preparatory work. International, governmental and non-governmental organizations liaising with the IEC also participate in this preparation. IEC collaborates closely with the International Organization for Standardization (ISO) in accordance with conditions determined by agreement between the two organizations.
- 2) The formal decisions or agreements of IEC on technical matters express, as nearly as possible, an international consensus of opinion on the relevant subjects since each technical committee has representation from all interested IEC National Committees.
- 3) IEC Publications have the form of recommendations for international use and are accepted by IEC National Committees in that sense. While all reasonable efforts are made to ensure that the technical content of IEC Publications is accurate, IEC cannot be held responsible for the way in which they are used or for any misinterpretation by any end user.
- 4) In order to promote international uniformity, IEC National Committees undertake to apply IEC Publications transparently to the maximum extent possible in their national and regional publications. Any divergence between any IEC Publication and the corresponding national or regional publication shall be clearly indicated in the latter.
- 5) IEC itself does not provide any attestation of conformity. Independent certification bodies provide conformity assessment services and, in some areas, accept IEC marks of conformity. IEC is not responsible for any services carried out by independent certification bodies.
- 6) All users should ensure that they have the latest edition of this publication.
- 7) No liability shall attach to IEC or its directors, employees, servants or agents including individual experts and members of its technical committees and IEC National Committees for any personal injury, property damage or other damage of any nature whatsoever, whether direct or indirect, or for costs (including legal fees) and expenses arising out of the publication, use of, or reliance upon, this IEC Publication or any other IEC Publications.
- 8) Attention is drawn to the normative references cited in this publication. Use of the referenced publications is indispensable for the correct application of this publication.
- 9) Attention is drawn to the possibility that some of the elements of this IEC Publication may be the subject of patent rights. IEC shall not be held responsible for identifying any or all such patent rights.

International Standard IEC 62047-32 has been prepared by subcommittee 47F: Micro-electromechanical systems, of IEC technical committee 47: Semiconductor devices.

The text of this International Standard is based on the following documents:

FDIS	Report on voting
47F/322/FDIS	47F/325/RVD

Full information on the voting for the approval of this International Standard can be found in the report on voting indicated in the above table.

This document has been drafted in accordance with the ISO/IEC Directives, Part 2.

A list of all parts in the IEC 62047 series, published under the general title *Semiconductor devices – Micro-electromechanical devices*, can be found on the IEC website.

The committee has decided that the contents of this document will remain unchanged until the stability date indicated on the IEC website under "<http://webstore.iec.ch>" in the data related to the specific document. At this date, the document will be

- reconfirmed,
- withdrawn,
- replaced by a revised edition, or
- amended.

**IMPORTANT – The 'colour inside' logo on the cover page of this publication indicates that it contains colours which are considered to be useful for the correct understanding of its contents. Users should therefore print this document using a colour printer.**

## SEMICONDUCTOR DEVICES – MICRO-ELECTROMECHANICAL DEVICES –

### Part 32: Test method for the nonlinear vibration of MEMS resonators

#### 1 Scope

This part of IEC 62047 specifies the test method and test condition for the nonlinear vibration of MEMS resonators. The statements made in this document apply to the development and manufacture for MEMS resonators.

#### 2 Normative references

The following documents are referred to in the text in such a way that none or all of their content constitutes requirements of this document. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

IEC 62047-1, *Semiconductor devices – Micro-electromechanical devices – Part 1: Terms and definitions*

#### 3 Terms and definitions

For the purposes of this document, the terms and definitions given in IEC 62047-1 and the following apply.

- IEC Electropedia: available at <http://www.electropedia.org/>
- ISO Online browsing platform: available at <http://www.iso.org/obp>

##### 3.1

##### **nonlinear vibration**

vibration whose displacement has a nonlinear relationship with the elastic restoring force, with the change of the vibration amplitude

##### 3.2

##### **nonlinear jump**

jump phenomenon of the frequency response curve when the vibration amplitude exceeds a certain threshold

##### 3.3

##### **frequency deviation**

deviation of the vibration frequency of the resonator in a closed-loop system from the natural frequency of the resonator

#### 4 Test parameters of nonlinear vibration of the resonators

Test parameters of nonlinear vibration of the resonators are:

- a) amplitude-frequency response of the nonlinear vibration,  $A(\omega)$ ;
- b) phase-frequency response of the nonlinear vibration,  $P(\omega)$ ;